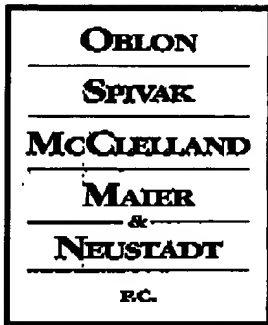


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TO	Paul Schanoski	September 7, 2005
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	COMPANY/FIRM	FAX #
	NUMBER OF PAGES INCLUDING COVER: 3	CONFIRM FAX: <input type="checkbox"/> YES <input checked="" type="checkbox"/> NO
FROM	Vincent K. Shier, Ph.D.	0160-0193-0 PCT
	NAME	OUR REFERENCE
	703-412-6461	09/463,961
	DIRECT PHONE #	YOUR REFERENCE

MESSAGE

Further to our telephone conversation, I enclose herewith copies of the documents filed on August 9, 2004. If I may be of further assistance to you, please do not hesitate to contact me.

Best Regards,
Vincent K. Shier, Ph.D.

Unless otherwise indicated or obvious from the nature of the transmittal, the information contained in this facsimile message is attorney privileged and confidential information intended for the use of the individual or entity named above. If the reader of this message is not the intended recipient or the employee or agent responsible to deliver it to the intended recipient, you are hereby notified that any dissemination, distribution or copying of this communication is strictly prohibited. If you have received this communication in error or are not sure whether it is privileged, please immediately notify us by telephone and return the original message to us at the above address via the U.S. Postal Service at our Expense. Thank You.

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DOCKET NO.: 0160-0193-0 PCT/hyc

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hiroshi IKEDA, et al.

SERIAL NUMBER: 09/463,961

GROUP: 1754

FILED: March 9, 2000

EXAMINER: Wayne A. LANGE

FOR: PROCESS AND APPARATUS FOR TREATING SEMICONDUCTOR
PRODUCTION EXHAUST GASES**REQUEST TO CORRECT TITLE OF INVENTION**MAIL STOP ISSUE FEE
COMMISSIONER FOR PATENTS
P.O. BOX 1450
ALEXANDRIA, VA 22313-1450

SIR:

In the matter of the above-identified application for patent, we hereby request correction of your records to reflect the correct title of the invention. The title of the invention should read as follows: **PROCESS AND APPARATUS FOR TREATING SEMICONDUCTOR PRODUCTION EXHAUST GASES.**

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.
Norman F. Oblon

Vincent K. Shier, Ph.D.
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(OSMMN 05/04)

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PRODUCTION EXHAUST GASES

REQUEST TO CORRECT FILING DATE

MAIL STOP ISSUE FEE
COMMISSIONER FOR PATENTS
P.O. BOX 1450
ALEXANDRIA, VA 22313-1450

SIR:

In the matter of the above-identified application, we hereby request correction of your records to reflect the correct filing date of the invention. The correct filing date of the invention should be: March 9, 2000, as evidenced by the copy of the date-stamped filing receipt.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.
Norman F. Oblon

Vincent K. Shier, Ph.D.
Registration No. 50,552

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(OSMMN 05/04)

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